

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/786,495

Confirmation No.: 3146

In re application of: Chun-Hung LIN

Filed: February 25, 2004

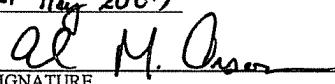
Technology Center/Art Unit: 2886

Examiner: NGUYEN, Sang H

Docket No.: 2003-0671(N1085-00243)

Customer No.: **54657**Title: METHOD TO PREDICT AND
IDENTIFY DEFOCUS WAFERS

I CERTIFY THAT THIS CORRESPONDENCE IS BEING
TRANSMITTED ELECTRONICALLY TO THE UNITED STATES
PATENT AND TRADEMARK OFFICE, ON

21 May 2007

SIGNATURE

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT

Sir:

This is in response to the Restriction Requirement in the Office Action dated April 17, 2007.

Remarks/Arguments begin on page 2 of this paper.